PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: DINESH CHOPRA	Examiner: Stanetta D. Isaac
Serial No.: 10/680,581	Group Art Unit: 2812
Confirmation No.: 5261	Att'y Docket: 2008.005782
Filed: October 7, 2003	Customer No.: 23720
For: METHOD OF CONTROLLING METAL FORMATION PROCESSES USING ION IMPLANTATION, AND SYSTEM FOR PERFORMING SAME	

RESPONSE TO OFFICE ACTION DATED OCTOBER 3, 2006

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This paper is submitted in response to the Office Action dated October 3, 2006, for which the three-month date for response is January 3, 2007.

No fees are believed to be due in connection with the present paper. However, should any fees be required under 37 C.F.R. §§ 1.16 to 1.21, the Director is authorized to deduct such fees from Williams, Morgan & Amerson, P.C. Deposit Account No. 50-0786/2008.005782.

Reconsideration of the application in view of the following amendments and remarks is respectfully requested.